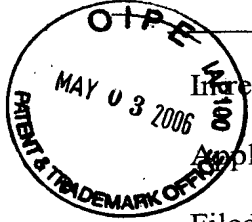


IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Inventor application of: Lee et al.

Application No.: 10/649,351

Filed: August 26, 20003

Title: METHOD FOR REDUCING
TUNGSTEN FILM ROUGHNESS AND
IMPROVING STEP COVERAGE

Attorney Docket No.:
NOVLP033X1/NVLS-000498X1

Examiner: Pham, Thanhha S.

Group: 2813

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on May 1, 2006 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: _____

Leslie Russell

**INFORMATION DISCLOSURE STATEMENT
BEFORE FINAL ACTION OR NOTICE OF ALLOWANCE
(37 CFR §§ 1.56 AND 1.97(c))**

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449, a copy of which is attached, may be material to examination of the above-identified patent application. Applicants submit this reference in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make this citation of official record in this application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that this reference indeed constitutes prior art.

This Information Disclosure Statement is being filed after the mailing date of the first Office Action on the merits, or after three months of the filing date of this application, whichever event occurred last, but it is believed before the mailing date of either: (i) a final action under §1.113 or (ii) a notice of allowance under §1.311, whichever occurs first.

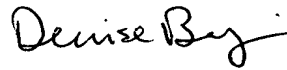
Accompanying this Information Disclosure Statement is

- ☐ a statement as specified in 37 CFR 1.97(e); or
- ☒ the fee set forth in 37 CFR 1.17(p).

If fees are due, enclosed is our Check No. 11896 for \$180.00 in payment of the Information Disclosure Statement Fee. If it is determined that any additional fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NOVLP033X1).

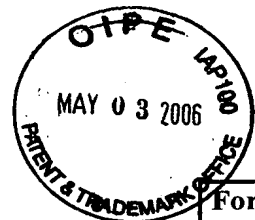
Respectfully submitted,

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Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary)	Atty Docket No. NOVLP033X1/NVLS- 000498X1	Application No.: 10/649,351
	Applicant: Lee et al. Filing Date August 26, 2003	Group 1762

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
	A1	5,956,609	09.1999	Lee et al.			
	A2	2003/0104126 A1	06.2003	Fang et al.			

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub- class	Translation	
							Yes	No

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	C1	Levy et al., "Deposition of Tungsten Nitride", Novellus Systems, Inc., filed December 16, 2005, Application No. 11/305,368, pages 1-39. [NOVLP063D1/NVLS-2615D1].
	C2	U.S. Office Action mailed December 28, 2005, from U.S. Application No. 10/815,560 [NOVLP096/NVLS-2902].
	C3	U.S. Office Action mailed April 17, 2006, from U.S. Application No. 10/815,560 [NOVLP096/NVLS-2902].
	C4	Wongsenakhum et al., "Reducing Silicon Attack and Improving Resistivity of Tungsten Nitride Film", Novellus Systems, Inc., filed February 6, 2006, Application No. 11/349,035, pages 1-26. [NOVLP138/NVLS-3094]
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.